

# Jun-Young Park

## List of Publications by Year in descending order

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42  
papers

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citations

623734

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43  
docs citations

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times ranked

720  
citing authors

| #  | ARTICLE   | IF  | CITATIONS |
|----|---|-----|-----------|
| 1  | Power Reduction in Punch-Through Current-Based Electro-Thermal Annealing in Gate-All-Around FETs. <i>Micromachines</i> , 2022, 13, 124.   | 2.9 | 3         |
| 2  | Impact of Iterative Deuterium Annealing in Long-Channel MOSFET Performance. <i>Materials</i> , 2022, 15, 1960.  | 2.9 | 9         |
| 3  | N-Type Nanosheet FETs without Ground Plane Region for Process Simplification. <i>Micromachines</i> , 2022, 13, 432.   | 2.9 | 9         |
| 4  | Vacuum Inner Spacer to Improve Annealing Effect during Electro-Thermal Annealing of Nanosheet FETs. <i>Micromachines</i> , 2022, 13, 987.   | 2.9 | 0         |
| 5  | Impact of Post-Metal Annealing With Deuterium or Nitrogen for Curing a Gate Dielectric Using Joule Heat Driven by Punch-Through Current. <i>IEEE Electron Device Letters</i> , 2021, 42, 276-279. | 3.9 | 5         |
| 6  | Inner Spacer Engineering to Improve Mechanical Stability in Channel-Release Process of Nanosheet FETs. <i>Electronics (Switzerland)</i> , 2021, 10, 1395.   | 3.1 | 9         |
| 7  | Gateless and Capacitorless Germanium Biristor with a Vertical Pillar Structure. <i>Micromachines</i> , 2021, 12, 899.   | 2.9 | 2         |
| 8  | Dielectric Engineering to Suppress Cell-to-Cell Programming Voltage Interference in 3D NAND Flash Memory. <i>Micromachines</i> , 2021, 12, 1297.  | 2.9 | 2         |
| 9  | A Study of High-Temperature Effects on an Asymmetrically Doped Vertical Pillar-Type Field-Effect Transistor. <i>IEEE Nanotechnology Magazine</i> , 2020, 19, 52-55.                               | 2.0 | 7         |
| 10 | Quantitative Analysis of High-Pressure Deuterium Annealing Effects on Vertically Stacked Gate-All-Around SONOS Memory. <i>IEEE Transactions on Electron Devices</i> , 2020, 67, 3903-3907.        | 3.0 | 15        |
| 11 | Curing of Aged Gate Dielectric by the Self-Heating Effect in MOSFETs. <i>IEEE Transactions on Electron Devices</i> , 2020, 67, 777-788.   | 3.0 | 21        |
| 12 | Self-Heating Effects in 3-D Vertical-NAND (V-NAND) Flash Memory. <i>IEEE Transactions on Electron Devices</i> , 2020, 67, 5505-5510.  | 3.0 | 0         |
| 13 | A Comparative Study of the Curing Effects of Local and Global Thermal Annealing on a FinFET. <i>IEEE Journal of the Electron Devices Society</i> , 2019, 7, 954-958.                              | 2.1 | 4         |
| 14 | Curing of Hot-Carrier Induced Damage by Gate-Induced Drain Leakage Current in Gate-All-Around FETs. <i>IEEE Electron Device Letters</i> , 2019, 40, 1909-1912.                                    | 3.9 | 14        |
| 15 | Nanoscale FET-Based Transduction toward Sensitive Extended-Gate Biosensors. <i>ACS Sensors</i> , 2019, 4, 1724-1729.  | 7.8 | 28        |
| 16 | Suppression of Self-Heating Effects in 3-D V-NAND Flash Memory Using a Plugged Pillar-Shaped Heat Sink. <i>IEEE Electron Device Letters</i> , 2019, 40, 212-215.                                  | 3.9 | 12        |
| 17 | Demonstration of Thermally-Assisted Programming With High Speed and Improved Reliability for Junctionless Nanowire NOR Flash Memory. <i>IEEE Nanotechnology Magazine</i> , 2019, 18, 1110-1113.   | 2.0 | 2         |
| 18 | Electro-Thermal Erasing at $10^4$ -Fold Faster Speeds in Charge-Trap Flash Memory. <i>IEEE Electron Device Letters</i> , 2019, 40, 196-199.   | 3.9 | 6         |

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|----|--|------|-----------|
| 19 | Demonstration of a Curable Nanowire FinFET Using Punchthrough Current to Repair Hot-Carrier Damage. IEEE Electron Device Letters, 2018, 39, 180-183.   | 3.9  | 20        |
| 20 | A Comparative Study on Hot-Carrier Injection in 5-Story Vertically Integrated Inversion-Mode and Junctionless-Mode Gate-All-Around MOSFETs. IEEE Electron Device Letters, 2018, 39, 4-7.                         | 3.9  | 26        |
| 21 | Localized Electrothermal Annealing with Nanowatt Power for a Silicon Nanowire Field-Effect Transistor. ACS Applied Materials & Interfaces, 2018, 10, 4838-4843.  | 8.0  | 7         |
| 22 | A Recoverable Synapse Device Using a Three-Dimensional Silicon Transistor. Advanced Functional Materials, 2018, 28, 1804844.   | 14.9 | 34        |
| 23 | On-Chip Curing by Microwave for Long Term Usage of Electronic Devices in Harsh Environments. Scientific Reports, 2018, 8, 14953.   | 3.3  | 4         |
| 24 | Electrothermal Annealing to Enhance the Electrical Performance of an Exfoliated MoS <sub>2</sub> Field-Effect Transistor. IEEE Electron Device Letters, 2018, , 1-1.   | 3.9  | 7         |
| 25 | Sanitization of Data in Nanoscale Flash Memory by Thermal Erasing and Reuse of Storage. Physica Status Solidi (A) Applications and Materials Science, 2018, 215, 1800194.  | 1.8  | 2         |
| 26 | Investigation of Self-Heating Effects in Gate-All-Around MOSFETs With Vertically Stacked Multiple Silicon Nanowire Channels. IEEE Transactions on Electron Devices, 2017, 64, 4393-4399.                         | 3.0  | 31        |
| 27 | A Novel Technique for Curing Hot-Carrier-Induced Damage by Utilizing the Forward Current of the PN-Junction in a MOSFET. IEEE Electron Device Letters, 2017, 38, 1012-1014.                                      | 3.9  | 21        |
| 28 | Nano-electromechanical Switch Based on a Physical Unclonable Function for Highly Robust and Stable Performance in Harsh Environments. ACS Nano, 2017, 11, 12547-12552.   | 14.6 | 34        |
| 29 | Electro-Thermal Annealing Method for Recovery of Cyclic Bending Stress in Flexible a-IGZO TFTs. IEEE Transactions on Electron Devices, 2017, 64, 3189-3192.  | 3.0  | 22        |
| 30 | LF Noise Analysis for Trap Recovery in Gate Oxides Using Built-In Joule Heater. IEEE Transactions on Electron Devices, 2017, 64, 5081-5086.  | 3.0  | 6         |
| 31 | Improved Technique for Extraction of Effective Mobility by Considering Gate Bias-Dependent Inversion Charges in a Floating-Body Si/SiGe pMOSFET. Journal of Nanoscience and Nanotechnology, 2017, 17, 3247-3250. | 0.9  | 1         |
| 32 | Controllable electrical and physical breakdown of poly-crystalline silicon nanowires by thermally assisted electromigration. Scientific Reports, 2016, 6, 19314.   | 3.3  | 12        |
| 33 | Physically Transient Memory on a Rapidly Dissoluble Paper for Security Application. Scientific Reports, 2016, 6, 38324.  | 3.3  | 36        |
| 34 | First demonstration of a wrap-gated CNT-FET with vertically-suspended channels. , 2016, , .  |      | 1         |
| 35 | Sustainable electronics for nano-spacecraft in deep space missions. , 2016, , .  |      | 19        |
| 36 | Joule Heating to Enhance the Performance of a Gate-All-Around Silicon Nanowire Transistor. IEEE Transactions on Electron Devices, 2016, 63, 2288-2292.   | 3.0  | 8         |

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|----|--|------|-----------|
| 37 | Threshold Voltage Tuning Technique in Gate-All-Around MOSFETs by Utilizing Gate Electrode With Potential Distribution. <i>IEEE Electron Device Letters</i> , 2016, 37, 1391-1394.                                      | 3.9  | 5         |
| 38 | Electrothermal Annealing (ETA) Method to Enhance the Electrical Performance of Amorphous-Oxide-Semiconductor (AOS) Thin-Film Transistors (TFTs). <i>ACS Applied Materials &amp; Interfaces</i> , 2016, 8, 23820-23826. | 8.0  | 14        |
| 39 | Three-Dimensional Fin-Structured Semiconducting Carbon Nanotube Network Transistor. <i>ACS Nano</i> , 2016, 10, 10894-10900.   | 14.6 | 16        |
| 40 | Local Electro-Thermal Annealing for Repair of Total Ionizing Dose-Induced Damage in Gate-All-Around MOSFETs. <i>IEEE Electron Device Letters</i> , 2016, 37, 843-846.  | 3.9  | 22        |
| 41 | Self-Curable Gate-All-Around MOSFETs Using Electrical Annealing to Repair Degradation Induced From Hot-Carrier Injection. <i>IEEE Transactions on Electron Devices</i> , 2016, 63, 910-915.                            | 3.0  | 33        |
| 42 | Vertically Integrated Multiple Nanowire Field Effect Transistor. <i>Nano Letters</i> , 2015, 15, 8056-8061.  | 9.1  | 60        |